Special Issue

Micro/Nanofabrication of 2D Materials and Devices

Message from the Guest Editor

Since graphene's discovery two decades ago, the field of 2D materials has expanded rapidly in both material diversity and fabrication methodologies. Many significant advancements in 2D research stem directly from remarkable progress in nanofabrication techniques. These methods now enable unprecedented precision in manipulating atomically thin layers, offering exceptional control over parameters like strain, twistangle, cleanliness, and stacking order. A symbolic example of these enabling techniques is the evolution of exfoliation and transfer methods, culminating in the "tear-and-stack" approach. This innovation directly led to the discovery of emergent flat bands in twisted heterostructures. While this was predicted theoretically, their experimental realization was previously hindered by stringent precision requirements for twist-angle engineering. The "tear-and-stack" technique thus paved the way for unlocking novel phases of matter in 2D materials, underscoring how innovative nanofabrication can facilitate groundbreaking discoveries. This special issue will highlight recent developments in the nanofabrication of 2D materials and related systems.

Guest Editor

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